

## Terahertz detectors based on the room temperature Nb<sub>5</sub>N<sub>6</sub> microbolometers

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Terahertz (THz) detectors based on the room-temperature (RT) microbolometers consisting of a Nb<sub>5</sub>N<sub>6</sub> thin film microbridge and a dipole planar antenna are reported. Due to the high temperature coefficient of the resistance (TCR), which is as high as  $-0.7\% \text{ K}^{-1}$ , of the Nb<sub>5</sub>N<sub>6</sub> thin film, such an antenna-coupled microbolometer is quite suitable for detecting THz signals. Previously, THz detectors working at 0.1 THz have been reported [1]. Here, the properties at 0.22-0.33 THz will be presented.

The microbolometers consist of a gold dipole planar antenna and a microbridge, which is the core element and is made of properly patterned Nb<sub>5</sub>N<sub>6</sub> thin film. To effectively couple the applied THz power onto the Nb<sub>5</sub>N<sub>6</sub> microbridge, a resonant dipole antenna is used. The dipole antenna is inserted into a 120  $\mu\text{m}$  by 210  $\mu\text{m}$  stub, which is also used to connect to the bias circuits. The software named HFSS is used to carry out numerical simulations for this antenna structure and to optimize the sizes. In the process of Nb<sub>5</sub>N<sub>6</sub> microbolometer chip fabrication, a SiO<sub>2</sub>/Si (100) combination substrate is used, where SiO<sub>2</sub> with 100 nm thick, is deposited by thermal oxidation on Si(100) substrate with high resistivity ( $\rho > 1000 \Omega\text{-cm}$ ). Such a combination is chosen because of its low loss at lower band of THz frequencies and ease of fabricating an air-bridge, underneath the Nb<sub>5</sub>N<sub>6</sub> microbridge. Then, we used radio frequency (RF) magnetron sputtering to deposit a Nb<sub>5</sub>N<sub>6</sub> film (120 nm thick) on the substrate. The film was patterned into microbridges using photolithography and reactive ion etching (RIE). The dipole antenna was then integrated with the Nb<sub>5</sub>N<sub>6</sub> microbridge by depositing a 5-nm-thick aluminum film firstly, a 220-nm-thick gold one later, and then pattern the antenna into the right shape and size as designed by the software. Finally, an air-bridge, which reduces the effective thermal conductance of the substrate to further enhance the responsivity, was formed under the Nb<sub>5</sub>N<sub>6</sub> microbridge by etching 1  $\mu\text{m}$  of the Si part of the SiO<sub>2</sub>/Si (100) combination substrate.

The DC responsivity at RT, calculated from the measured current-voltage (I-V) curve of the Nb<sub>5</sub>N<sub>6</sub> microbolometer, is about  $-760 \text{ V/W}$  at the bias current of 0.19 mA. A typical noise voltage as low as 10 nV/√Hz yields a low noise equivalent power (NEP) of  $1.3 \times 10^{-11} \text{ W/}\sqrt{\text{Hz}}$  at modulation frequency above 4 kHz. The best RF responsivity at 0.28 THz, characterized using a normal measuring method for the infrared devices, is about 580 V/W, with the corresponding NEP being  $1.7 \times 10^{-11} \text{ W/}\sqrt{\text{Hz}}$ . In order to further test the performance of Nb<sub>5</sub>N<sub>6</sub> microbolometer, we constructed a quasi-optical type receiver by attaching it to a hyperhemispherical silicon lens and the result shows that the best responsivity of the receiver is about 320 V/W at 0.24 THz, which corresponding the NEP of  $3.1 \times 10^{-11} \text{ W/}\sqrt{\text{Hz}}$ .

Using above detectors, an active imaging system at 0.22 THz has been constructed using a Cassegrain reflector with the diameter of 30 cm. The special resolution of about 1.41 cm is obtained. Also, this work could offer a candidate to develop a large scale focal plane array (FPA) with simple technique and low costs. The details will be discussed in the presentation.

### Acknowledgements

This work was supported by the National Basic Research Program of China ("973" Program) (No. 2014CB339800), the National High Technology Research Program of China ("863" Program) (No. 2011AA010204) and the National Natural Science Foundation of China (Nos. 11227904). Also, it was partially supported by the Fundamental Research Funds for the Central Universities and Jiangsu Key Laboratory of Advanced Techniques for Manipulating Electromagnetic Waves.

### References

1. L. Kang et. al., "A room temperature Nb<sub>5</sub>N<sub>6</sub> microbolometer for detecting 100 GHz radiation" 20<sup>th</sup> ISSTT, Charlottesville, 20-22 April 2009, P7E.